

Micron: le Memorie del Futuro

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Process R&D

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Italy



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Micron at a Glance

Micron is one of the world's leading providers of advanced semiconductor memory solutions



Founded: October 1978, Boise, ID

FY2010 Net Sales to Date (FQ1-2010, FQ2-2010, FQ3-2010): \$5.9 billion

NASDAQ Symbol: MU

Employees: ~23,000 worldwide

Products: DRAM, Flash memory, SSDs, CMOS image sensors and memory modules in multiple technologies, generations, configurations, and packages.

Markets We Serve: Micron's products are designed to meet the diverse needs of computing, networking, server, consumer, mobile, automotive, and industrial applications.

Patents: 17,230

Process R&D Global Presence



California



Idaho (HQ)



Colorado



New Hampshire



Belgium



Italy



India

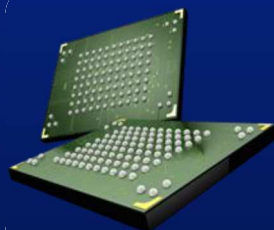


Singapore



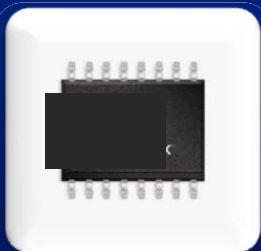
Taiwan

Broadest Product Portfolio



NAND

- Discrete SLC and MLC: 128Mb-64Gb
- Small/Large/Very Large Page+
- Managed: SLC/MLC eMMC (Auto Grade), Compact Flash, ClearNAND
- 1.8V & 3V Solutions
- Comprehensive package portfolio
- Evolution path to Phase Change Memory



NOR

- Complete parallel & serial portfolio (512kB-2Gb+)
- 1.8 & 3V solutions
- Comprehensive package portfolio
- Automotive Grade Solutions
- Evolution path to Phase Change Memory



DRAM

- Full portfolio from legacy to leading-edge
- SDR, DDR 1/2/3, densities up to 4GB
- DDR3 offerings down to 1.35V and up to DDR3-1600
- Automotive Grade Solutions

Digital Media Group Products

Cards for Photography



Mobile Cards



Gaming Cards



Solid State Drives



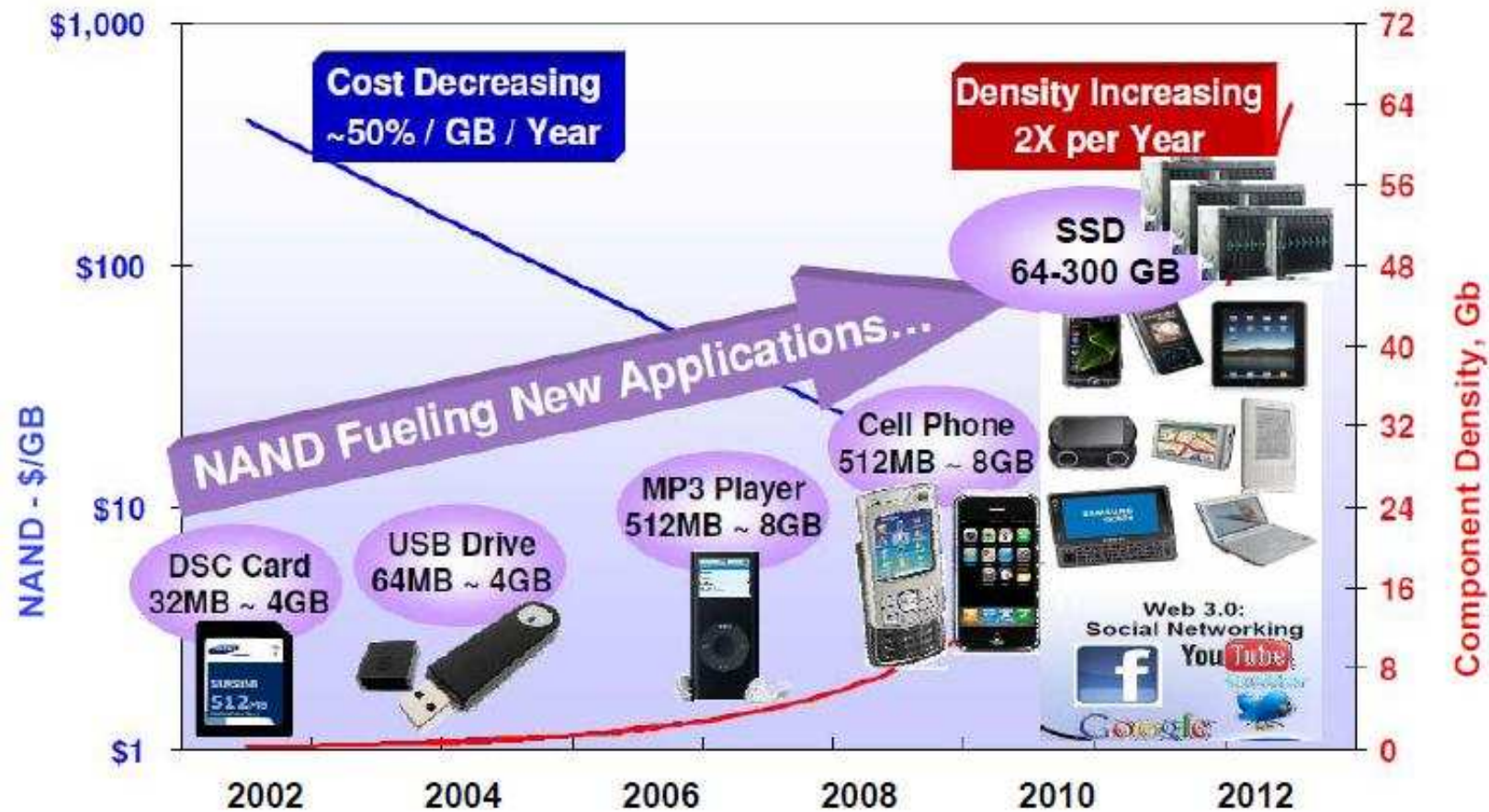
USB Flash Drives



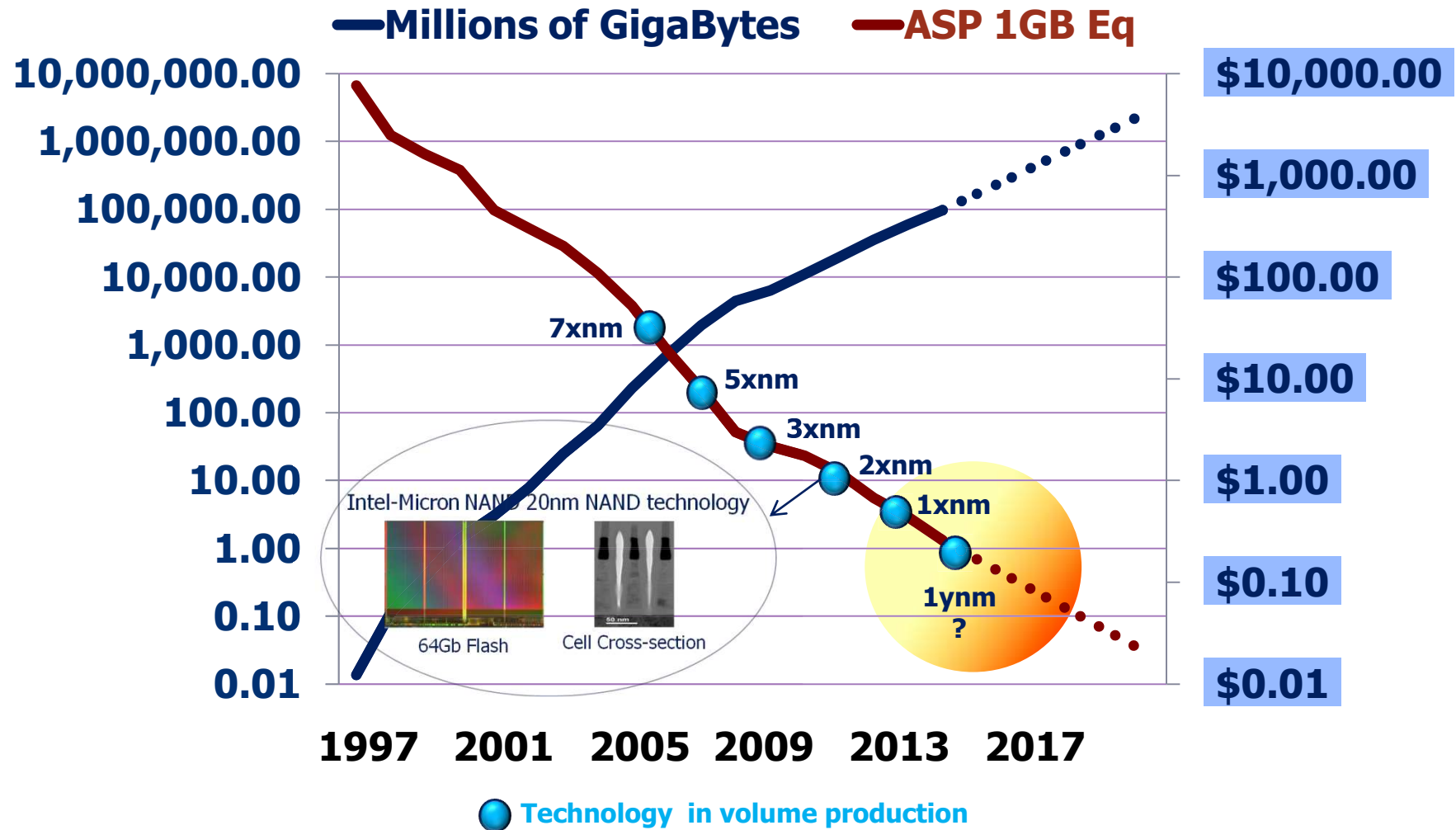
DRAM Modules



Semiconductor Memory in Everyday Life

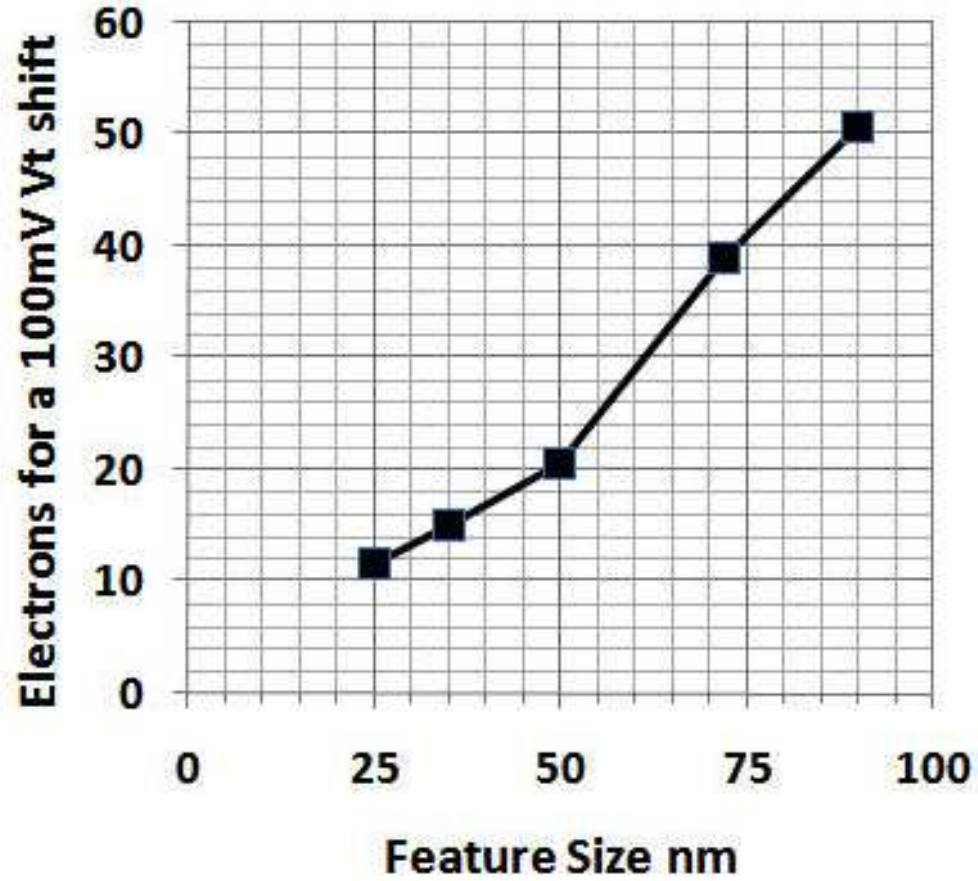


Memory Technology Nodes Over Time



Source: Gartner

NAND Scaling Running Out of Electrons



NAND Replacement Strategy!

- Just need to figure out when NAND hits the wall and be standing on tracks with a better technology
- Technology needs to be competitive in most metrics
- Scale vertically to continue cost reduction



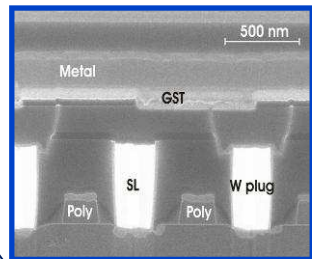
Emerging Memories

Near-term And Long-term Alternatives

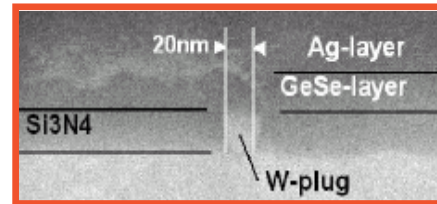
FERAM



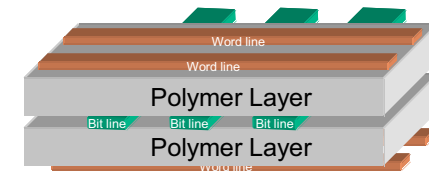
PCM



PMC RRAM



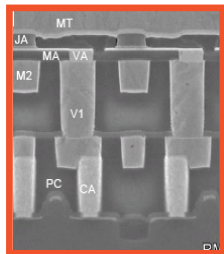
Polymer FeRAM



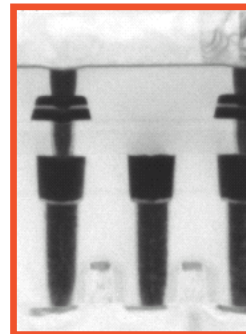
CNT



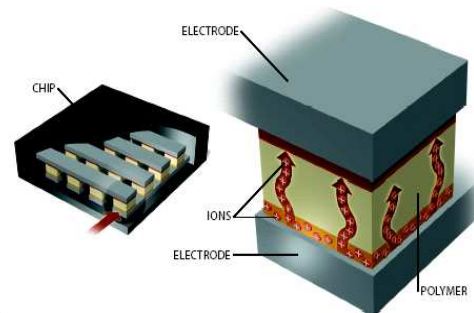
MRAM



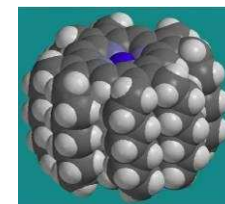
MOx-RRAM



Polymer RRAM



Molecular



Phase Change Memory (PCM)

Chalcogenide Materials

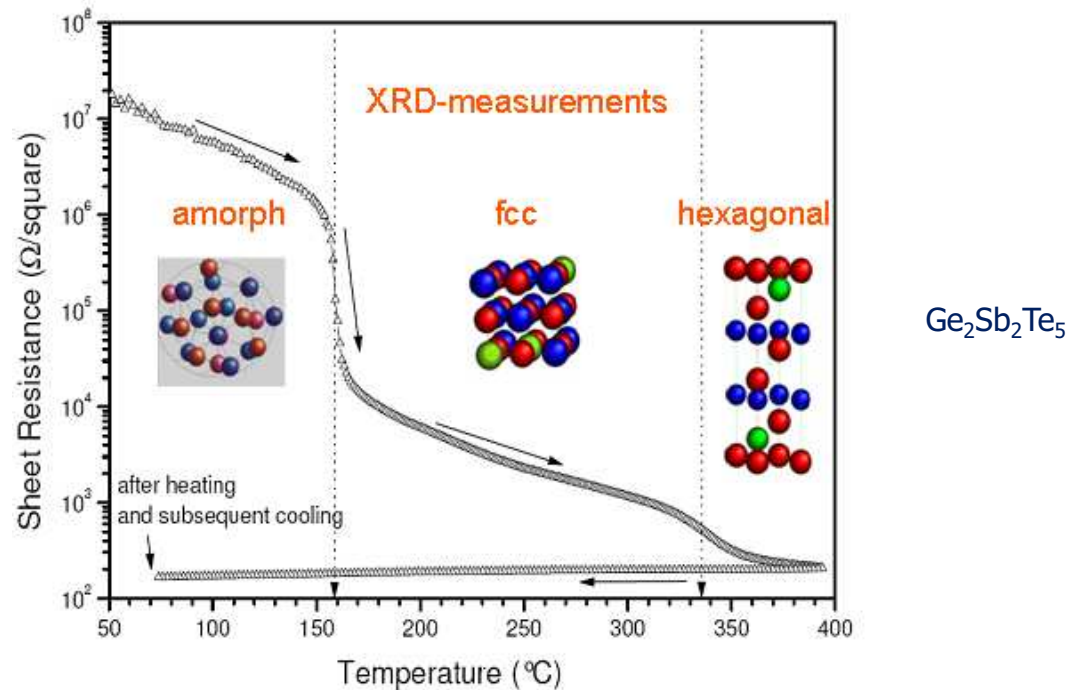
	13	IIIA	14	IVA	15	VA	16	VIA	17	VIIA	HELIUM	
	5	10.811	6	12.011	7	14.007	8	15.999	9	18.998	10	20.180
	B		C		N		O		F		Ne	
	BORON		CARBON		NITROGEN		OXYGEN		FLUORINE		NEON	
	13	26.982	14	28.086	15	30.974	16	32.06	17	35.453	18	39.948
	Al		Si		P		S		Cl		Ar	
	ALUMINUM		SILICON		PHOSPHORUS		SULPHUR		CHLORINE		ARGON	
409	31	69.723	32	72.64	33	74.922	34	78.96	35	79.904	36	83.798
	Ga		Ge		As		Se		Br		Kr	
	GALLIUM		GERMANIUM		ARSENIC		SELENIUM		BROMINE		KRYPTON	
241	49	114.82	50	118.71	51	121.76	52	127.60	53	126.90	54	131.29
	In		Sn		Sb		Te		I		Xe	
	INDIUM		TIN		ANTIMONY		TELLURIUM		IODINE		XENON	
159	81	204.38	82	207.2	83	208.98	84	(209)	85	(210)	86	(222)
	Tl		Pb		Bi		Po		At		Rn	
	THALLIUM		LEAD		BISMUTH		POLONIUM		ASTATINE		RADON	

Chalcogenic Elements

- Chalcogenide materials are alloys with an element of the VI group of the periodic table, usually combined with IV and V group elements (As_2S_3 , As_2Te_3 , SnSb_2Te_4 , GeTe , Sb_2Te_3 , $\text{Ge}_2\text{Sb}_2\text{Te}_5$...)

Phase Transition

- Certain alloys containing one/more group VI elements (chalcogenide) exhibit reversible transition between the disordered (amorphous) and ordered (crystalline) atomic structure

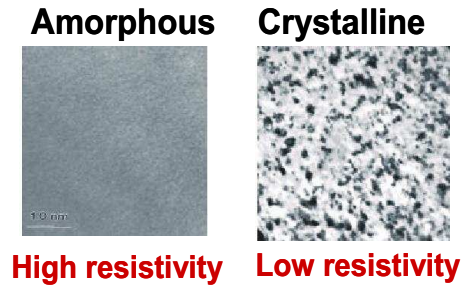


- Phase transition, induced by temperature, is a very fast mechanism (tens-hundreds of ns)

Phase Change Memory Concept

Storing mechanism

amorphous / poly-crystal phases of a chalcogenide alloy, usually $\text{Ge}_2\text{Sb}_2\text{Te}_5$ (GST)

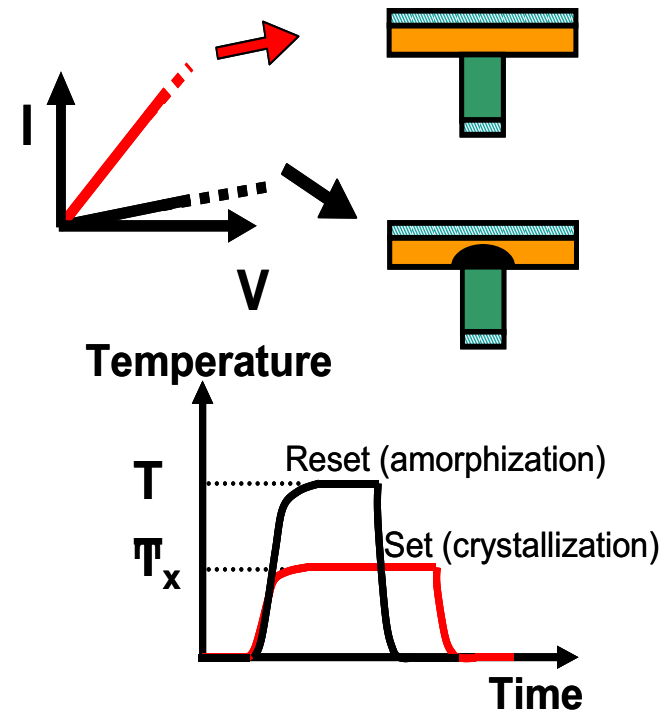


Reading mechanism

resistance change of the GST
amorphous \rightarrow high resistance ($\sim 10\Omega\cdot\text{cm}$) \rightarrow reset state
crystalline \rightarrow low resistance ($\sim 10\text{m}\Omega\cdot\text{cm}$) \rightarrow set state

Writing mechanism

self-heating due to current flow (Joule effect)
melting temperature ($T_m \sim 630\text{C}$, for $t_{\text{RESET}} \sim 10\text{-}100\text{ns}$)
crystallization temperature ($T_x \sim 400\text{C}$, for $t_{\text{SET}} \sim 100\text{-}1000\text{ns}$)



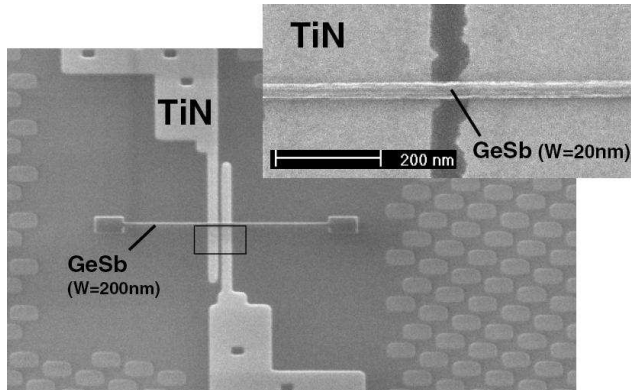
Phase Change Memory Key Attributes

- Non Volatility
- Flexibility
 - ▶ No Erase, Bit alterable, Continuous Writing
- Lower power consumption than RAM
- Fast Writes
- Read bandwidth and writing throughput
- eXecution in Place
- Extended endurance

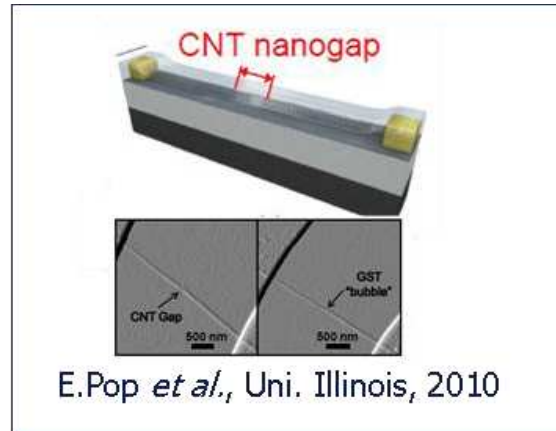
Attributes	PCM	EEPROM	NOR	NAND	DRAM
Non-Volatile	Yes	Yes	Yes	Yes	No
Scaling	sub-2x nm	n.a.	3x nm	2x nm	3x nm
Granularity	Small/Byte	Small/Byte	Large	Large	Small/Byte
Erase	No	No	Yes	Yes	No
Software	Easy	Easy	Moderate	Hard	Easy
Power	~Flash	~Flash	~Flash	~Flash	High
Write Bandwidth	1- 15+ MB/s	13-30 KB/s	0.5-2 MB/s	10+ MB/s	100+ MB/s
Read Latency	50 - 100 ns	200-200 ns	70-100 ns	15 - 50 us	20 - 80 ns
Endurance	10 ⁶⁺	10 ⁵ - 10 ⁶	10 ⁵	10 ⁴⁻⁵	Unlimited

Le PCM forniscono un nuovo set di caratteristiche che combinano componenti di NVM con DRAM

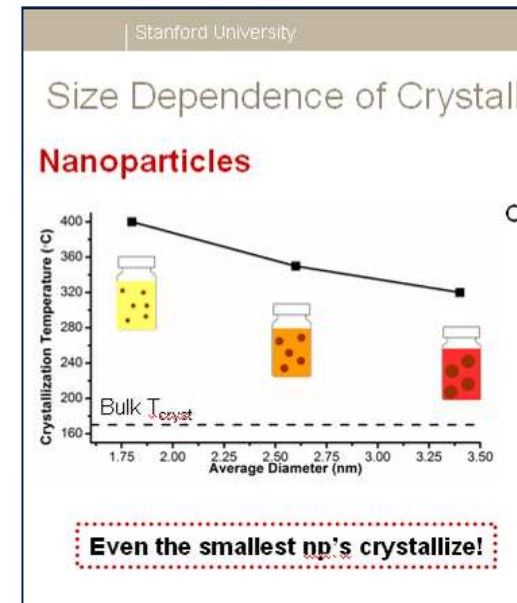
Ultimate Scalability of PCM



Y. C. Chen et al., IEDM 2006

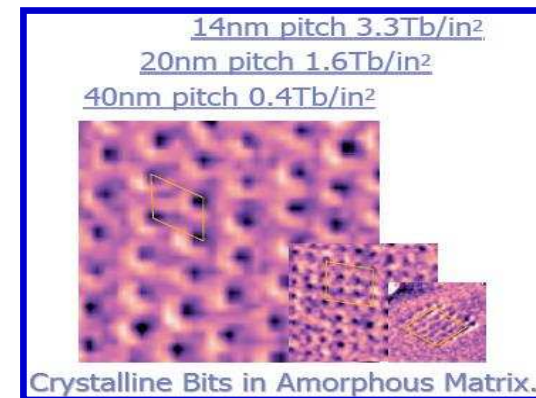


E. Pop *et al.*, Uni. Illinois, 2010



P. Wong, EPCOS 2010

- Device functionality demonstrated on 60 nm² active area
- Reset current <10uA
- Phase change mechanism appears scalable to at least ~5nm



C. Lam, SRC NVM Forum 2004

Micron Technology in Italia



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Micron Italy Outline



Production:	Imagers - NOR - PCM
Process R&D:	Imagers - NOR - PCM
Design R&D:	NAND - NOR - PCM - e.MMC
Business Units:	WSG - ESG
Marketing & Sales:	DRAM - NAND - NOR - PCM

Agrate R&D - R2 Technology Development Center

- Facility 200mm wafers
- Clean rooms : $\approx 6000 \text{ m}^2$
- People Professionality
 - Researchers
 - Engineers/Technicians
 - Manufacturing Operators
- Research Labs & Activites
 - Electrical labs. and Physical/chemical lab.
 - Material and Device Research lab. of National Research Council
 - Strong links with Universities and key European Research Centers



State of the Art 200 mm Equipment

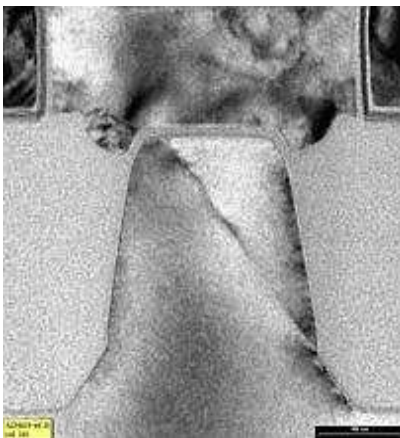
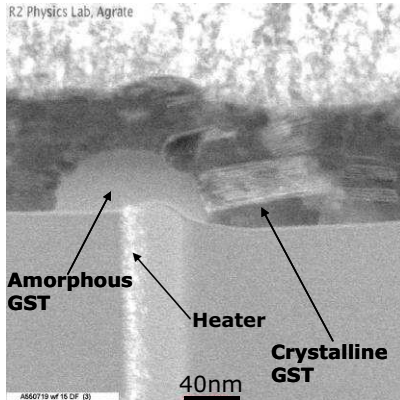
Advanced equipment for production and development of NVM processes.

- 193nm High Numerical Aperture Litho
- Immersion Lithography
- Cu Back-end for high aspect ratio structure
- State of the art Plasma Etching Systems
- High-K Dielectric Atomic Layer Deposition
- Multisputter PVD for Chalcogenides deposition (Phase Change Memory)

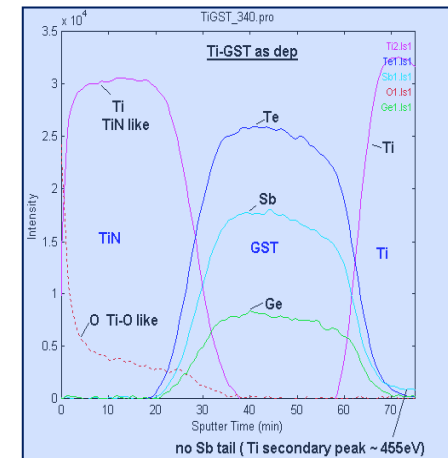
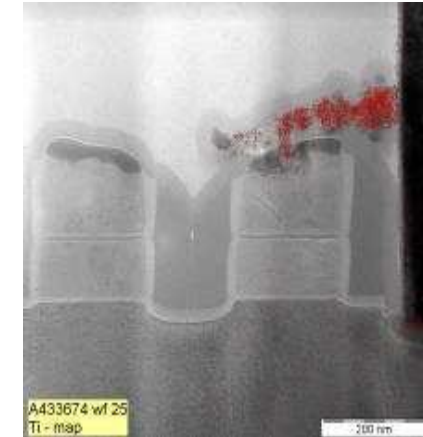
Cooperation with Equipment Vendors, national and international labs, to study and integrate new materials



R2 Physics Laboratory



- **Microscopy Service for R2**
 - ▶ Technology development
- **Defects & Contamination in Si**
 - ▶ Defect reduction in process
 - ▶ Si contamination control
- **Physical Failure Analysis**
 - ▶ Yield enhancement
- **Materials Analysis**
 - ▶ New materials characterization
 - ▶ Process problem solving



SEM, FIB, TEM for electron microscopy
Auger, XPS, TOF-SIMS, XRD for materials analysis



Focused on Memory | Engineered for Innovation

